

In the Claims

Claims 1-6 (Cancelled)

1 7. (Original) An electron optical column comprising:
2 means for generating an electron beam;
3 a focus lens; and
4 an electrostatic scanning deflector situated above said focus lens, said scanning deflector
5 comprising a first deflector and a second deflector configured to provide telecentric scanning of
6 said electron beam on a specimen substrate positioned below said focus lens.

1 8. (Currently amended) An electron optical column as in claim [[1]] 7, wherein said first
2 deflector and said second deflector generate electric fields of opposite polarities.

1 9. (Currently amended) An electron optical column as in claim [[1]] 7, wherein said first
2 deflector and said second deflector generate deflection fields of different strengths.

1 10. (Currently amended) An electron optical column as in claim [[1]] 7, wherein said
2 scanning deflector comprises octupole deflectors.

1 11. (Currently amended) An electron optics assembly as in claim [[1]] 7, wherein said
2 scanning deflector comprises titanium alloy elements brazed to a ceramic substrate.

1 12. (Original) An electron optics assembly for a multi-column electron optical system
2 comprising:
3 means for generating a multiplicity of electron beams;
4 a multiplicity of focus lenses, configured such that there is a corresponding focus lens for
5 each column; and
6 a multiplicity of scanning deflectors situated above said focus lenses, such that there is a
7 corresponding scanning deflector for each column, each said scanning deflector comprising a
8 first deflector and a second deflector configured to provide telecentric scanning of said electron
9 beams on a specimen substrate positioned below said focus lenses.

1 13. (Currently amended) An electron optics assembly as in claim ~~[[6]]~~ 12, wherein said
2 scanning deflectors are electrostatic deflectors.

1 14. (Currently amended) An electron optics assembly as in claim ~~[[7]]~~ 12, wherein said first
2 deflectors and said second deflectors generate electric fields of opposite polarities.

1 15. (Currently amended) An electron optical column as in claim ~~[[6]]~~ 12, wherein said first
2 deflectors and said second deflectors generate deflection fields of different strengths.

1 16. (Currently amended) An electron optics assembly as in claim ~~[[6]]~~ 12, wherein said
2 scanning deflectors are octupole deflectors.

1 17. (Currently amended) An electron optics assembly as in claim ~~[[6]]~~ 12, wherein each of
2 said scanning deflectors comprises titanium alloy elements brazed to a ceramic substrate.

In the Drawings

A replacement drawing is attached indicating FIG. 17a and FIG. 17b as indicated on page 8, lines 5-8 of the specification.

Attachment: Replacement Sheet
Annotated Sheet Showing Changes